

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Intl.  
Appl. No. : PCT/JP2003/016441  
Applicant : Shigeru UMENO et al.  
Intl. Appl.  
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TC/A.U. : Not Assigned  
Examiner : Not Assigned  
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**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

February 16, 2005

Sir:

Prior to calculation of the fee and examination on the merits of the above-identified patent application, please amend the application as follows:

U.S. National Stage of  
PCT/JP2003/016441  
PRELIMINARY AMENDMENT

**PATENT**

**IN THE TITLE:**

MANUFACTURING METHOD ~~FOR MANUFACTURING~~ OF SILICON WAFER